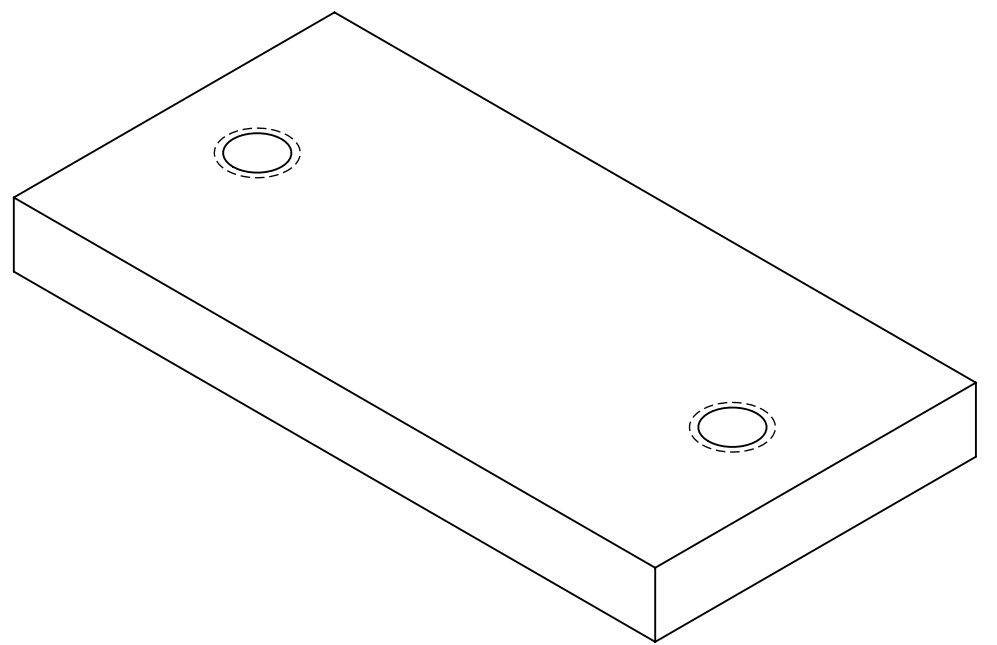
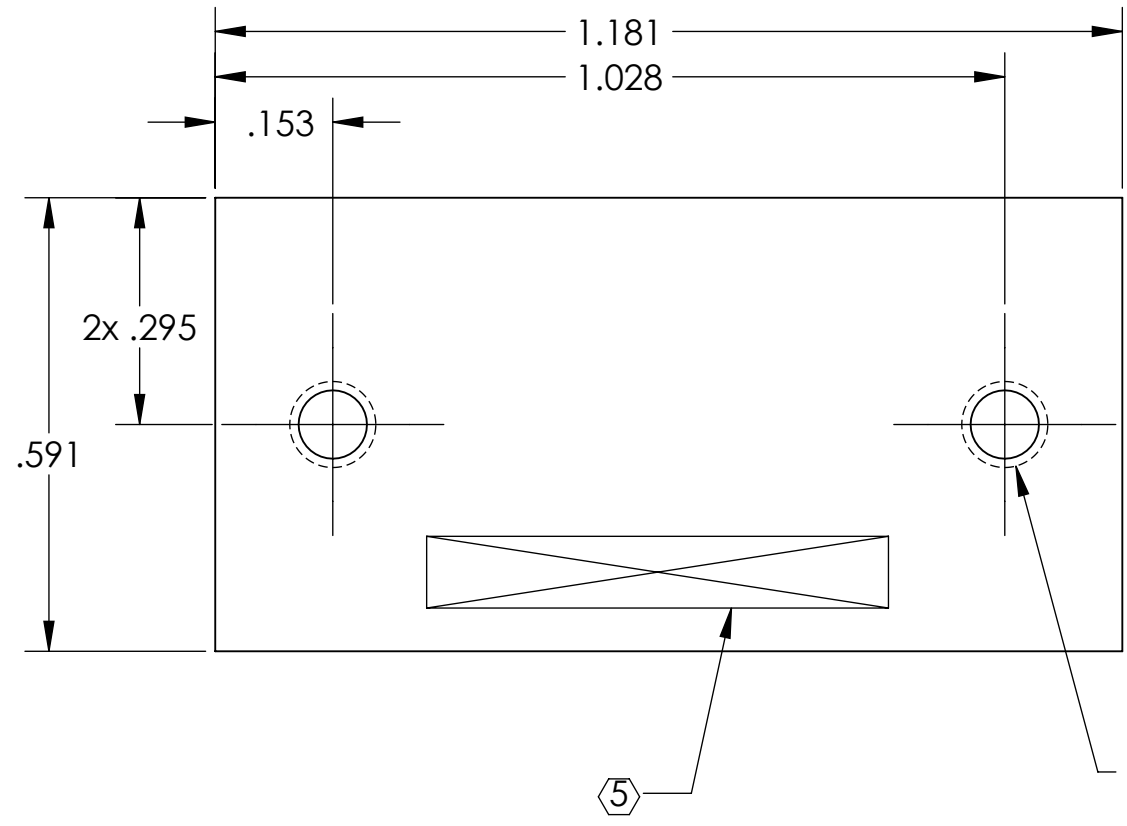


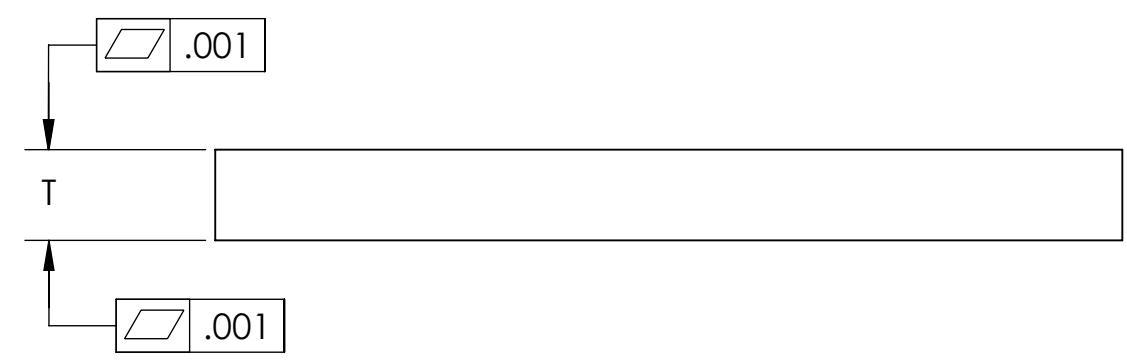
8 7 6 5 4 3 2 1

NOTES CONTINUED:
 5. MACHINE PART NUMBER & TYPE AND SERIAL NUMBER. NO RAISED MATERIAL AROUND MARKING
 6. APPROXIMATE WEIGHT: SEE TABLE
 7. MACHINE ALL SURFACES TO REMOVE OXIDES AND MILL FINISH. USE OF ABRASIVE REMOVAL TECHNIQUES IS NOT ALLOWED.
 8. ALL PARTS SHALL BE MANUFACTURED IN ACCORDANCE WITH LIGO SPECIFICATION E0900364.

REV.	DATE	DCN #	DRAWING TREE #
v1	19 APR 2013	E1300287-x0	-
-	-	-	-
-	-	-	-



2x #4-40 GH7 (+.003) THRU
 MINIMAL CHAMFERS TO PRESERVE THREAD DEPTH



PART NUMBER	T (mm)	T (in) +/- .003	WEIGHT (g)
D1300354-01	1.00	.0394	3.56
D1300354-02	1.25	.0492	4.45
D1300354-03	1.50	.0591	5.34
D1300354-04	1.75	.0689	6.23
D1300354-05	2.00	.0787	7.12
D1300354-06	2.25	.0886	8.01
D1300354-07	2.50	.0984	8.90

NOTES AND TOLERANCES: (UNLESS OTHERWISE SPECIFIED)

1. INTERPRET DRAWING PER ASME Y14.5-1994.
 2. REMOVE ALL SHARP EDGES, .005-.015.
 3. DO NOT SCALE FROM DRAWING.
 4. ALL MACHINING FLUIDS MUST BE FULLY SYNTHETIC, FULLY WATER SOLUBLE AND FREE OF SULFUR, SILICONE, AND CHLORINE.

DIMENSIONS ARE IN
 TOLERANCES:
 .XX ± .01
 .XXX ± .005
 ANGULAR ± 1°

MATERIAL INVAR 36 **FINISH** 63 μinch

SYSTEM ADVANCED LIGO **SUB-SYSTEM** ISC **NEXT ASSY** D1201439

CALIFORNIA INSTITUTE OF TECHNOLOGY
MASSACHUSETTS INSTITUTE OF TECHNOLOGY

PART NAME aLIGO aLIGO DIODE MOUNT SHIM

DESIGNER J.LEWIS **DATE** 19 APR 2013 **SIZE** B **DWG. NO.** D1300354 **REV.** V1
DRAFTER J.LEWIS **DATE** 19 NOV 2012

CHECKER
APPROVAL

SCALE: 1:1 **PROJECTION:** **SHEET 1 OF 1**

D1300354 OMC PD SHIM, PART PDM REV: X-000, DRAWING PDM REV: X-000

8 7 6 5 4 3 2 1